

**TITLE OF THE INVENTION: APPARATUS FOR MATERIALS
PROCESSING BY STIMULATED LIGHT EMISSION AND METHOD OF
ITS UTILIZATION**

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ABSTRACT of the DISCLOSURE

A materials processing apparatus and a method of its utilization for surface modification and/or cleaning, sterilization, disinfection, film deposition, and etching of discrete objects, powder-like substances and continuous media by generating a stimulated light emission in the chamber wherein treated surfaces are placed. The apparatus may operate by itself or together with plasma chamber and/or means for adding an active monomer vapor.